

## MEASURED DATA DISPLAYING METHOD FOR EPMA

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### Abstract

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PURPOSE:To grasp the distribution state of an element on a sample face at real time by scanning an electron beam according to the information of the specified analysis positions along the desired curve on a sample with an input device such as a mouth or a track ball and scanning the raster of a CRT display synchronously with it.

CONSTITUTION:Analysis positions are specified along the desired curve on a sample 2 with an input device such as a mouth 18 or a track ball, and an electron beam is scanned according to the information of the specified analysis positions. The raster of a CRT display 14 is scanned synchronously with it, and the locus corresponding to the electron beam scan and the profile of the X-ray strength detected from the sample 2 using this locus as a base line are displayed on a screen. The distribution state of a specific element at the optional position can be thereby grasped at real time.

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